



IP 1764

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

In the Application of:

David Skee

Serial No.: 10/572,860

Filed: March 22, 2006

Atty. File No.: 1595 WO/US

Title: Alkaline, Post Plasma Etch/Ash Residue
Removers and Photoresist Stripping
Compositions Containing Metal-Halide
Corrosion Inhibitors

) Group Art Unit: 1764

) Examiner: Not yet assigned

CERTIFICATE OF MAILING

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FIRST SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with duties imposed by 37 CFR §1.56 and means for complying therewith according to 37 CFR §§1.97-1.98, the references listed on the attached Form PTO/SB/08A are called to the attention of the US Patent & Trademark Office in relation to the present application.

No representation is made that the cited references are the only art or that the cited references represents the best art. The Examiner is urged to consider all of the cited references and to make an independent evaluation of the teachings and materiality of each.

Since this correspondence is being submitted prior to a first Office Action on the merits, it is believed that no fee is due. However, if a fee is required for entry of this correspondence, please charge Deposit Account No. 13-1160.

Respectfully submitted,

Christine R. Cooke

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